

REPLY UNDER 37 CFR 1.116 EXPEDITED PROCEDURE TECHNOLOGY CENTER 2800

Attorney Docket No. 051876.P352

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of:

Byung-Seop Hong

Serial No. 10/648,183

Filed: August 25, 2003

METHOD FOR RELEASING STRESS DURING SEMICONDUCTOR DEVICE FABRICATION

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450 Examiner: Trung Q. Dang

Art Unit: 2823

O.K TOENTEL T.DAMA 4/3/06

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Sir:

In response to the Final Office Action mailed January 10, 2006, regarding the abovereferenced application, Applicant respectfully requests entry of the amendment set forth below in consideration of the remarks that follow.